

# Yuanwei Lin

## List of Publications by Year in descending order

Source: <https://exaly.com/author-pdf/4929892/publications.pdf>

Version: 2024-02-01

24  
papers

600  
citations

759233

12  
h-index

794594

19  
g-index

24  
all docs

24  
docs citations

24  
times ranked

1336  
citing authors

#	ARTICLE	IF	CITATIONS
1	A universal etching-free transfer of MoS <sub>2</sub> films for applications in photodetectors. <i>Nano Research</i> , 2015, 8, 3662-3672.	10.4	94
2	Oxidative Etching-Assisted Synthesis of Centimeter-Sized Single-Crystalline Graphene. <i>Advanced Materials</i> , 2016, 28, 3152-3158.	21.0	81
3	Direct observation of single-molecule hydrogen-bond dynamics with single-bond resolution. <i>Nature Communications</i> , 2018, 9, 807.	12.8	78
4	An organic-inorganic hybrid perovskite logic gate for better computing. <i>Journal of Materials Chemistry C</i> , 2015, 3, 10793-10798.	5.5	77
5	Ultra-thin wafer technology and applications: A review. <i>Materials Science in Semiconductor Processing</i> , 2020, 105, 104681.	4.0	48
6	Nanocrystalline Perovskite Hybrid Photodetectors with High Performance in Almost Every Figure of Merit. <i>Advanced Functional Materials</i> , 2018, 28, 1705589.	14.9	42
7	Graphene-DNAzyme junctions: a platform for direct metal ion detection with ultrahigh sensitivity. <i>Chemical Science</i> , 2015, 6, 2469-2473.	7.4	40
8	Novel exciton dissociation behavior in tin-lead organohalide perovskites. <i>Nano Energy</i> , 2016, 27, 638-646.	16.0	28
9	Revealing Charge- and Temperature-Dependent Movement Dynamics and Mechanism of Individual Molecular Machines. <i>Small Methods</i> , 2019, 3, 1900464.	8.6	21
10	Chemically Engineered Substrates for Patternable Growth of Two-Dimensional Chalcogenide Crystals. <i>ACS Nano</i> , 2016, 10, 10317-10323.	14.6	16
11	Deep Dry Etching of Silicon with Scallop Size Uniformly Larger than 300 nm. <i>Silicon</i> , 2019, 11, 651-658.	3.3	15
12	Ultrahigh Photogain Nanoscale Hybrid Photodetectors. <i>Small</i> , 2015, 11, 2856-2861.	10.0	14
13	Uniformity improvement of deep silicon cavities fabricated by plasma etching with 12-inch wafer level. <i>Journal of Micromechanics and Microengineering</i> , 2019, 29, 105010.	2.6	10
14	The application of the scallop nanostructure in deep silicon etching. <i>Nanotechnology</i> , 2020, 31, 315301.	2.6	8
15	Detection of Mercury Ion with High Sensitivity and Selectivity Using a DNA/Graphene Oxide Hybrid Immobilized on Glass Slides. <i>Biosensors</i> , 2021, 11, 300.	4.7	8
16	Chemical Modification of Graphene and Its Applications. <i>Acta Chimica Sinica</i> , 2014, 72, 277.	1.4	8
17	Perspective on chymotrypsin detection. <i>New Journal of Chemistry</i> , 2020, 44, 20921-20929.	2.8	3
18	Transparent graphene electrodes based hybrid perovskites photodetectors with broad spectral response from UV-visible to near-infrared. <i>Nanotechnology</i> , 2022, 33, 085204.	2.6	3

#	ARTICLE	IF	CITATIONS
19	Estimating the Etching Depth Limit in Deep Silicon Etching. , 2019, , .		2
20	Highly sensitive detection for cocaine using an aptamer-modified molybdenum disulfide/gold nanoparticle microarray. New Journal of Chemistry, 2020, 44, 13466-13471.	2.8	2
21	Towards Tilt-Free in Plasma Etching. Journal of Micromechanics and Microengineering, 0, , .	2.6	1
22	Towards Microstructures with Ultrahigh Aspect-Ratio and Verticality in Deep Silicon Etching. , 2020, , .		1
23	Molecular Physics: Revealing Charge- and Temperature-Dependent Movement Dynamics and Mechanism of Individual Molecular Machines (Small Methods 12/2019). Small Methods, 2019, 3, 1970041.	8.6	0
24	A Segmented Plasma Etching Method for 2.5D/3D Through Silicon Vias. , 2021, , .		0